EUROPEAN COMMISSION

HORIZON 2020 PROGRAMME TOPIC H2020-LCE-2016-RES-CCA-RIA Improved electrolysis for distributed hydrogen production

GA No. 727523

Next – generation interdigitated back-contacted silicon heterojunction solar cells and modules by design and process innovations



NextBase – Public Summary

Work package 6 – IBC-SHJ process integration for mass production



| Work package | 6: IBC-SHJ process integration for mass production | |
|----------------------------|--|------------|
| Dissemination level | Public (PU) | |
| Status | Version 1 | 2017-01-12 |
| Related deliverables | D6.1, D6.2, D6.3 | |
| Document type | Ongoing: will be completed after every finished related deliverable. | |

Disclaimer/ Acknowledgment



Copyright ©, all rights reserved. This document or any part thereof may not be made public or disclosed, copied or otherwise reproduced or used in any form or by any means, without prior permission in writing from the NextBase Consortium. Neither the NextBase Consortium nor any of its members, their officers, employees or agents shall be liable or responsible, in negligence or otherwise, for any loss, damage or so uncertained by any agree as a result of the use in any memory or form of any knowledge information or

expense whatever sustained by any person as a result of the use, in any manner or form, of any knowledge, information or data contained in this document, or due to any inaccuracy, omission or error therein contained.

All Intellectual Property Rights, know-how and information provided by and/or arising from this document, such as designs, documentation, as well as preparatory material in that regard, is and shall remain the exclusive property of the NextBase Consortium and any of its members or its licensors. Nothing contained in this document shall give, or shall be construed as giving, any right, title, ownership, interest, license or any other right in or to any IP, know-how and information.

This project has received funding from the European Union's Horizon 2020 research and innovation programme under grant agreement No 727523. The information and views set out in this publication does not necessarily reflect the official opinion of the European Commission. Neither the European Union institutions and bodies nor any person acting on their behalf, may be held responsible for the use which may be made of the information contained therein.



Public summary

Deliverable 6.1

"Tool specification for high quality silicon deposition and in-situ masking"

A new R&D reactor combining both the deposition of ultra-thin new silicon layers with built-in patterning option will be manufactured. The goal is to manufacture IBC SHJ solar cells using shadow masks to reach high efficiency solar cells with a minimum of process steps. The development of this new technology will be structured around two main topics. First, the deposition of high quality silicon layers in order to reach very low contact resistance values with a novel type of silicon junction. Next, the development of a masking solution inside the reactor to pattern the silicon layers with very narrow tails width, allowing reaching very high aspect ratio. The combination of such new patterned silicon layers with state of the art passivation quality will trigger the development of very high efficiency IBC SHJ solar cells at a competitive cost.

Deliverable 6.2

"Tool manufacturing, testing and pilot cell fabrication: SHJ double side contacted cells with FF>80%, precursors with layer patterning >2ms and Jo<10 wafers/hour" Due in month 18, March 2018

Deliverable 6.3

"IBC-SHJ cells processing with a throughput >10 wafers/hour" Due in month 24, September 2018